Docket No.: 4425-320 PATENT

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

: EXPEDITED PROCEDURE

Chien-Hsin LAI et al.

Response under 37 CFR 1.116

U.S. Patent Application No. 10/659,258

Confirmation No. 3535

Filed: September 11, 2003

Group Art Unit: 1763
Examiner: Karla A Moore

For: PLASMA APPARATUS AND METHOD CAPABLE OF ADAPTIVE

**IMPEDANCE MATCHING** 

Commissioner for Patents

P. O. Box 1450

Alexandria VA 22313-1450

## **AMENDMENT**

Sir:

In response to the Office Action of May 18, 2006 please amend the above-identified application as follows: